



Form 1449 (Modified) Information Disclosure Statement By Applicant (Use Several Sheets if Necessary)	Atty Docket No. NOVLP033X1/NVLS-000498X1	Application No.: 10/649,351
	Applicant: Lee et al. Filing Date August 26, 2003	Group 1762-2812

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
CL	A1	5,956,609	09.1999	Lee et al.			
CL	A2	2003/0104126 A1	06.2003	Fang et al.			

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
CL	C1	Levy et al., "Deposition of Tungsten Nitride", Novellus Systems, Inc., filed December 16, 2005, Application No. 11/305,368, pages 1-39. [NOVLP063D1/NVLS-2615D1].
CL	C2	U.S. Office Action mailed December 28, 2005, from U.S. Application No. 10/815,560 [NOVLP096/NVLS-2902].
CL	C3	U.S. Office Action mailed April 17, 2006, from U.S. Application No. 10/815,560 [NOVLP096/NVLS-2902].
CL	C4	Wongsenakhum et al., "Reducing Silicon Attack and Improving Resistivity of Tungsten Nitride Film", Novellus Systems, Inc., filed February 6, 2006, Application No. 11/349,035, pages 1-26. [NOVLP138/NVLS-3094]
Examiner <i>Chunyu Li</i>		Date Considered 7/11/06

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



Form 1449 (Modified) Information Disclosure Statement By Applicant (Use Several Sheets if Necessary)	Atty Docket No. NOVLP033X1/NVLS- 2498X1	Application No.: 10/649,351
	Applicant: Lee et al. Filing Date August 26, 2003	Group 1762 -2812

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
CL	A1	2001/0008808	07.2001	Gonzalez, Fernando			
CL	A2	2001/0014533	08.2001	Sun, Shih-Wei			
CL	A3	2001/0044041	11.2001	Badding et al.			
CL	A4	2001/0015494	08.2001	Ahn, Kie Y.			

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
CL	C1	U.S. Office Action mailed May 17, 2006, from U.S. Application No. 10/984,126 [NOVLP058D1/NVLS-2732D1].
CL	C2	U.S. Office Action mailed April 17, 2006, from U.S. Application No. 10/815,560 [NOVLP096/NVLS-2902].
Examiner <i>Chung Lu</i>		Date Considered 7/11/06

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.